

Notice of References Cited		Application/Control No. 10/070,286	Applicant(s)/Patent Under Reexamination BENZEL ET AL.	
		Examiner Anita K Alanko	Art Unit 1765	Page 1 of 1

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	B	US-5,352,635	10-1994	Tu et al.	438/53
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.